

## Low Differential Pressure Mass Flow Controller

### MC-3000S Series



#### ■ Outlines

- MC-3000S Series: Mass flow controller equipped with LINTEC's original low pressure differential device to operate at low differential pressure environment

#### ■ Features

- Low pressure differential device
- In addition to AsH<sub>3</sub> and PH<sub>3</sub> for ion implantation, this MFC is also applicable to solid state material and liquified gas without heating
- RS-485 digital interface
- LINTEC's unique ambient temperature-compensated sensor incorporated
- Highly functional upon installation of microprocessor
- Diaphragm valve with small dead volume
- High-speed and high performance piezoelectric actuator
- Long-term leak tightness ensured using metal seal
- By using metal case and various filters, stable operation can be achieved through reduction of radio frequency noises and electromagnetic field interferences

#### CE RoHS

Model	MC-3102S		
Flow rate in Nitrogen (Full scale)	2 ~ 10SCCM	~ 20SCCM	~ 30SCCM
Flow rate control range	2 ~ 100% F.S.		
Valve operation mode	Normally open, Normally closed		
Accuracy	±1.0% F.S.		
Repeatability	±0.2% F.S.		
Response time	2 sec		
Analog flow rate setting signal	0 ~ 5VDC		
Analog flow rate output signal	0 ~ 5VDC		
Operating differential pressure	8×10 <sup>2</sup> Pa ~ 1.33×10 <sup>5</sup> Pa	1.07×10 <sup>3</sup> Pa ~ 1.33×10 <sup>5</sup> Pa	1.33×10 <sup>3</sup> Pa ~ 1.33×10 <sup>5</sup> Pa
Withstand pressure	1MPa(G)		
Temperature coefficient	Zero	±0.02% F.S. / °C	
	Span	±0.02% F.S. / °C	±0.08% F.S. / °C
Operating temperature	5 ~ 50°C 0 ~ 80% RH		
Leak integrity	1×10 <sup>-11</sup> Pa · m <sup>3</sup> / sec He		
Materials exposed to gas	SUS316L, SUS304, PCTFE		
Seal materials	Au		
Power supply requirement	+15VDC±3% 100mA, -15VDC±3% 50mA		
Mounting position	Specified upon order placement		
Analog connector	Dsub 9pin		
Digital interface	RJ45/RS-485		
Control valve actuator	Piezoelectric actuator		
Weight	1.0kg		